

8/13/03

Form PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					ATTY. DOCKET NO. MI22-2382	PRIORITY SERIAL NO. Filed Herewith	
					APPLICANT Micron Technology, Inc.		
					PRIORITY FILING DATE 10/19/99		PRIORITY GROUP Unknown
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
VU	AA	4,341,662	7/82	Pfefferle			
	AB	4,431,750	2/84	McGinnis et al.			
	AC	4,714,693	12/87	Targos			
	AD	3,975,304	8/76	della Porta et al.			
	AE	3,856,709	12/74	Porta et al.			
	AF	5,525,570	6/96	Chakraborty et al.			
	AG	5,330,700	7/94	Soukup et al.			
VU	AH	4,719,442	1/88	Bohars et al.			
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
VU	AI	9-082666		Japan	—	—	Yes
VU	AJ	0 415 751 A1		EPO	—	—	No
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
VU	AK		Ju-Hong Kwan et al.; "Characterization of Pt Thin Films Deposited by Metallorganic Chemical Vapor Deposition for Ferroelectric Bottom Electrodes"; J. Electrochem. Soc., Vol. 144, No. 8, August 1997; pp. 2848-2854				
VU	AL		M. Ino et al.; "Rugged surface polycrystalline silicon film deposition and its application in a stacked dynamic random access memory capacitor electrode"; J. Vac. Sci. Technol. B 14(2), March/April 1996; pp. 751-756				
	AM						
	AN						
	AO						
EXAMINER			DATE CONSIDERED		03/17/05		
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

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U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
V	AA	5,639,685	6/97	Zahurak et al.			
	AB	5,917,213	6/99	Iyer et al.			
	AC	5,874,364	2/99	Nakabayashi et al.			
	AD	5,053,917	10/91	Miyasaka et al.			
	AE	5,208,479	5/93	Mathews et al.			
	AF	5,783,716	7/98	Baum et al.			
	AG	5,796,648	8/98	Kawakubo et al.			
V	AH	5,763,286	6/98	Figura et al.			
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
V	AI	5-67730		Japan			Yes
V	AJ	0 855 738 A2		EPO			No
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
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	AM						
	AN						
EXAMINER <u>HUNG JU</u>				DATE CONSIDERED <u>03/17/05</u>			
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10/19/99PRIORITY GROUP
Unknown

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
V	AA	5,320,978	6/94	Hsu			
	AB	6,033,953	3/00	Aoki et al.			
	AC	5,990,559	11/99	Marsh			
	AD	4,425,261	1/84	Stenius et al.			
	AE	6,175,129	1/01	Liu et al.			
	AF	6,010,744	1/00	Buskirk et al.			
	AG	5,555,486	9/96	Kingon et al.			
	AH	6,232,629	5/01	Nakamura			
V	AI	5,635,420	6/97	Nishioka			
	AJ						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
V	AK	JP 9051079	2/18/97	Japan				
	AL	JP 8017939	6/3/03	Japan				
	AM	JP 10173149	6/26/98	Japan				
V	AN	JP 10180098	7/7/98	Japan				
	AO							
	AP							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-2382	SERIAL NO. 10/642,454		
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Eugene P. Marsh			
				FILING DATE August 13, 2003	GROUP 2811		
U.S. PATENT DOCUMENTS							
Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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	AB						
	AC						
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	AJ						Yes <input checked="" type="checkbox"/> No <input type="checkbox"/>
	AK						
	AL						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)							
V	AM	Nasu, T. et al., "Study of Pt Bottom Electrodes Using High-Temperature Sputtering for Ferroelectric Memories with SrBi ₂ Ta ₂ O ₉ (SBTO) Film", Jpn. J. Appl. Phys. Vol. 37, Part 1, No. 7 (July 1998), pp. 4144-4148.					
	AN						
	AO						
EXAMINER HUNG. VU		DATE CONSIDERED 03/17/05					
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U.S. PATENT DOCUMENTS							
* Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
FOREIGN PATENT DOCUMENTS							
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VU	AJ	H09-239891	12/16/97	Japan	—	—	Yes <input checked="" type="checkbox"/> No <input type="checkbox"/>
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	AL						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
AM							
AN							
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